



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:) Docket No: LAM2P257
Ko et al.)
Application No: 09/894,230) Group Art Unit: 1756
Filed: June 27, 2001)
For: APPARATUS AND METHOD FOR ARGON)
PLASMA INDUCED ULTRAVIOLET LIGHT)
CURING STEP FOR INCREASING SILICON-)
CONTAINING PHOTORESIST SELECTIVITY)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 on December 17, 2003.

Signed: 
Michael L. Gencarella

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Advisory Action dated November 17, 2003. A one month extension of time is hereby petitioned for, to extend the period of response to December 17, 2003. Please amend the specification and consider the following arguments:

Amendments to the Specification begin on page 2 of this paper.

A current listing of the claims are provided for the Examiner's convenience which begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.